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RESPONSE UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE  
EXAMINING GROUP 2822**OFFICIAL**PATENT  
5589-00501 P658IN THE UNITED STATES PATENT AND TRADEMARK OFFICEIn re Application of:  
Xu et al.

Serial No. 09/854,177

Filed: May 10, 2001

For: METHOD AND SYSTEM FOR  
DETECTING METAL  
CONTAMINATION ON A  
SEMICONDUCTOR WAFERGroup Art Unit: 2822  
Examiner: Vockrodt, J.

Atty. Dkt. No. 5589-00501 P658

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Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria,  
VA 22313-1450, on the date indicated below:

02/02/2004  
Date  
Pamela GerikAMENDMENT: RESPONSE AFTER FINAL REJECTION PURSUANT TO 37 C.F.R. § 1.116Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir/ Madam:

This paper is submitted in response to the Final Office Action mailed December 2, 2003, to further highlight reasons why the application is in condition for allowance. Applicant submits the present paper complies with the requirements of 37 C.F.R. § 1.116.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks begin on page 10 of this paper.